


APPLICATION DATA SHEET

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Title of Invention	CLEANING COMPOSITION AND METHOD OF WASHING A SILICON WAFER		
Application Type : regular, utility Attorney Docket Number : NAUP0470USA1			
Correspondence address: Customer Number: 027765			
			
Continuing Data: This is a Division of US application number 09/683,247, filed 2001-12-05 , now PENDING.			
Inventors Information: <u>Inventor 1:</u> Applicant Authority Type: Inventor Citizenship: TW Given Name: Jeng-Wei Family Name: Yang Residence: City of Residence: Chang-Hua City Country of Residence: TW Address-1 of Mailing Address: No. 2-4, Yang-Ming St. Address-2 of Mailing Address: City of Mailing Address: Chang-Hua City State of Mailing Address: Postal Code of Mailing Address: Country of Mailing Address: TW Phone: Fax: E-mail: <u>Inventor 2:</u> Applicant Authority Type: Inventor Citizenship: TW			

Given Name: Tse-Yuan
Family Name: Lo
Residence:
City of Residence: Taipei City
Country of Residence: TW
Address-1 of Mailing Address: 6A, No. 76, Sec. 1, Chin-Shan S. Rd.
Address-2 of Mailing Address:
City of Mailing Address: Taipei City
State of Mailing Address:
Postal Code of Mailing Address:
Country of Mailing Address: TW
Phone:
Fax:
E-mail:

Attorney Information:

practitioner(s) at Customer Number:
027765



as our attorney(s) or agent(s) to prosecute the application identified above, and to transact all business in the United States Patent and Trademark Office connected therewith.